

Abstract

PLASMA SOURCE COIL FOR GENERATING PLASMA AND PLASMA CHAMBER USING THE SAME

5

10

Provided are a plasma source coil for generating plasma and a plasma chamber using the same. The plasma source coil receives power from a power supplier to generate uniformly plasma in a predetermined reaction space. The plasma source coil includes m (here, $m \geq 2$, and m is an integer) unit coils, each of which has a number n of turns (here, n is a positive real number). The unit coils extend from a coil bushing, which is located in the center of the plasma source coil and has a predetermined radius, and are arranged in a spiral shape around the coil bushing.

Figure 2